

LabClass QuantHE

Master Nanosciences

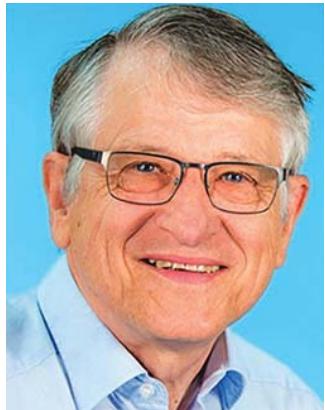


Julien Basset

Laboratoire de Physique des Solides – NS² group

Quantum Hall effect in Graphene

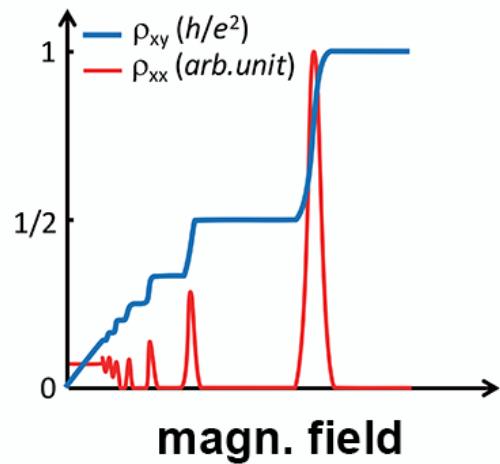
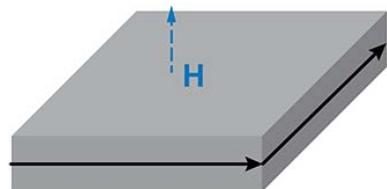
Klaus von Klitzing



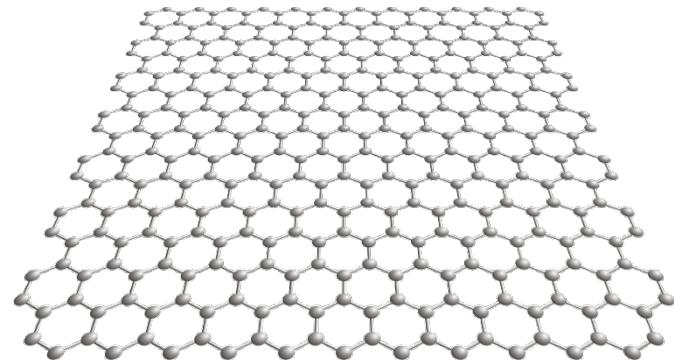
Andre Geim and Konstantin Novoselov



Integer quantum Hall
effect (1985)



Graphene (2010)



This labclass: Mixing of QHE and Graphene

A Two-parts lab class

1. Part 1: Microfabrication of the Graphene Hall Bar

- CVD grown graphene
- Transfer of graphene on doped Silicon
- Lithography of the micron-sized Hall bar
 - ✓ Photon lithography
 - ✓ RIE etching
 - ✓ E-gun evaporation of metals

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(C2N)



2. Part 2: Low temperature, high field measurement of the QHE

- Liquid Helium measurement stick
- Superconducting magnet
- Precision electronics

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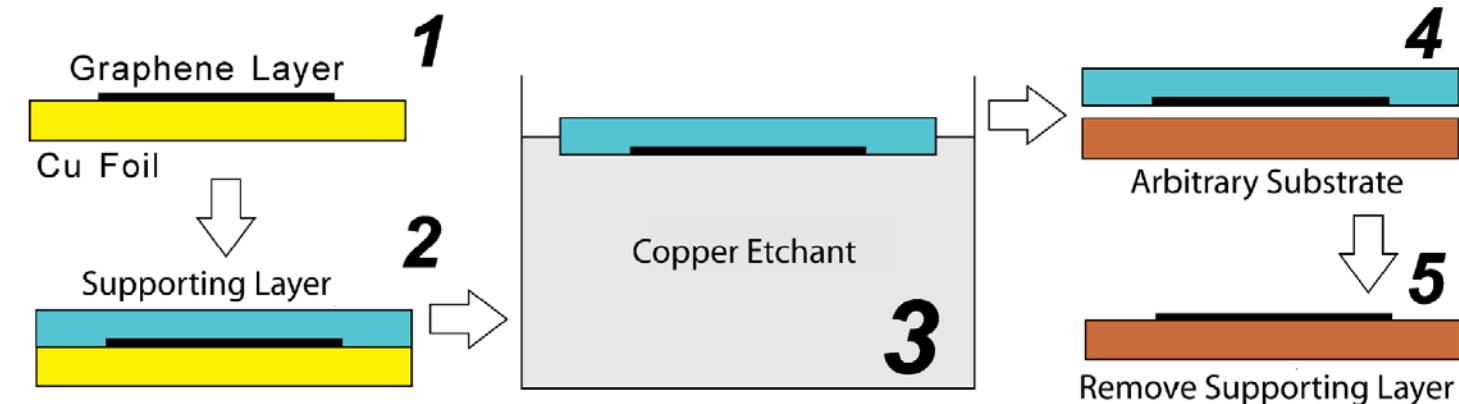
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CVD grown graphene transferred on doped Silicon substrate



1. Thin commercial copper foil
2. Thermal annealing to increase size of Cu cristallic domains
3. CVD of graphene ($T=1000^{\circ}\text{C}$, $\text{CH}_4 + \text{H}_2 + \text{Ar}$)
4. Spin PMMA resist as supporting layer
5. Etch Copper in Copper etchant solution
6. Transfer by fishing the graphene and dry
7. Remove PMMA in acetone



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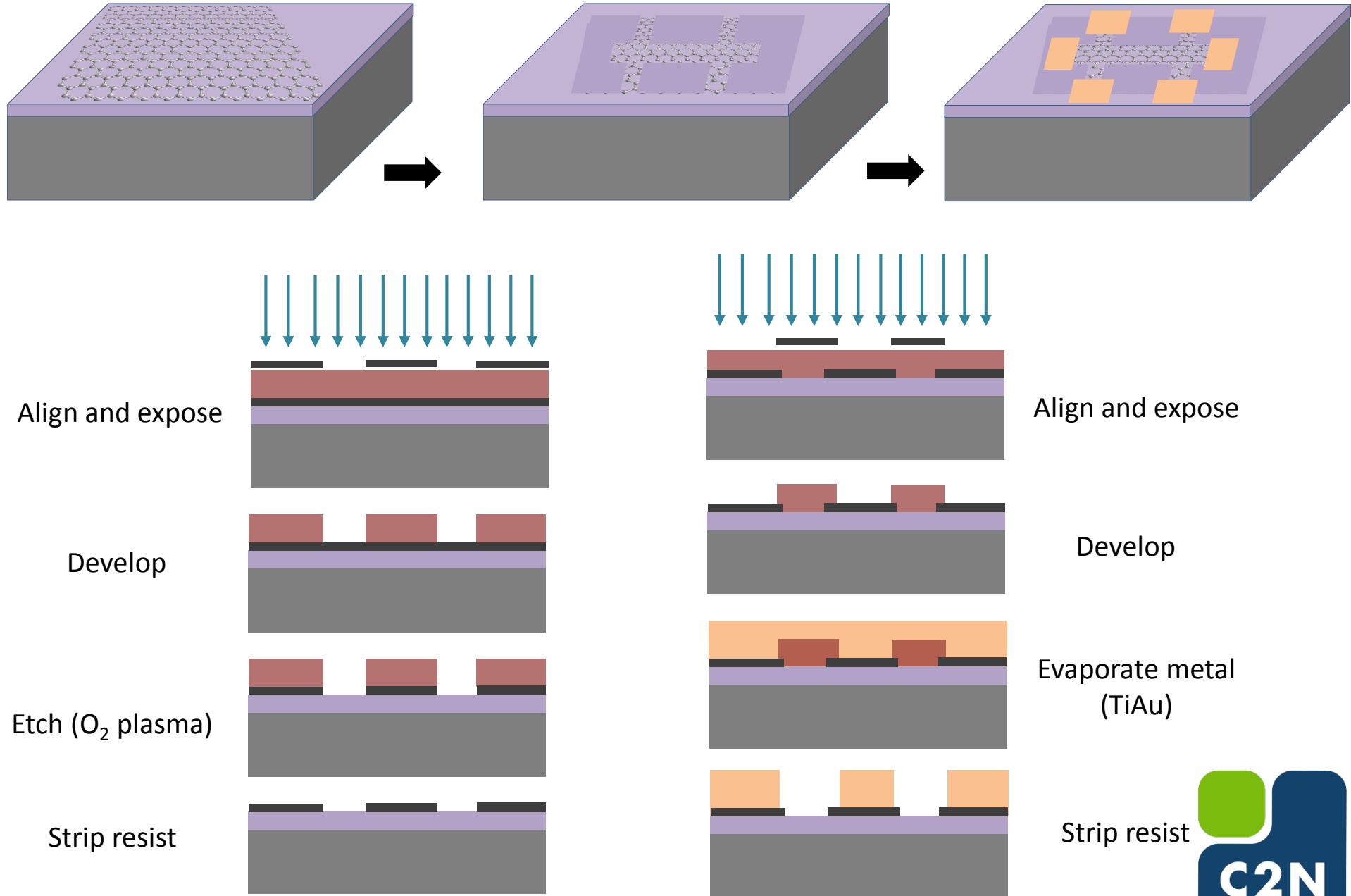
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Optical lithography of the Graphene Hall Bar



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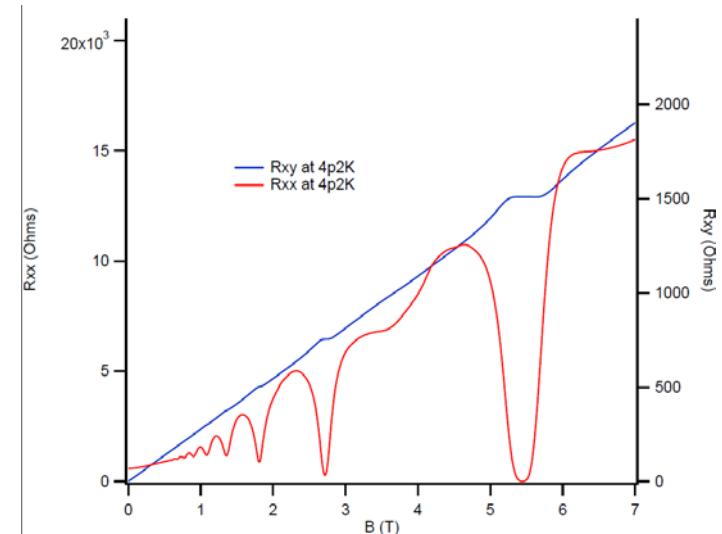


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Quantum Hall effect measurement @ T=4.2K, B=5T

- $R_{xx}(T)$
- @ T=4.2K, $R_{xx}=f(B)$, $R_{xy}=f(B)$
- Density modulation
- Verification of SdH broadening with a dc current
- Verification of Landauer-Büttiker formalism on a plateau
- ...



Some work at home

- 2 weeks to give a report (2 people) containing:
 - Fabrication techniques at C2N
 - ✓ Used tools and techniques
 - ✓ Difficulties encountered
 - Low-T measurements at LPS
 - ✓ Theoretical aspect of the QHE
 - ✓ Technical aspects of the measurement (low-T, low noise, high field)
 - ✓ Low-B, mid-B and High-B data
 - ✓ Extraction of density, mobility in several ways
 - ✓ Verification of conductance quantization
 - ✓ DC-current influence on Shubnikov-deHaas oscillations
 - ✓ Landauer-Büttiker picture verification

